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3Y SELF-ASSEMBLY AND RELATED ARTICLES
NVENTOR(S): OTTO Z. ZHOU ET AL.
APPLN. SERIAL NO.: UNASSIGNED SHEET 1 OF 9

FIGURE 1A

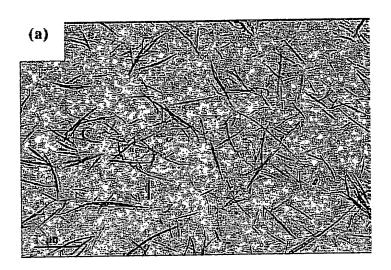
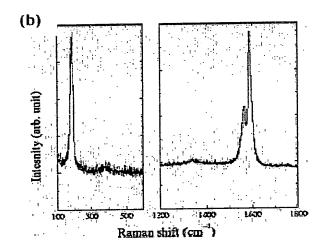
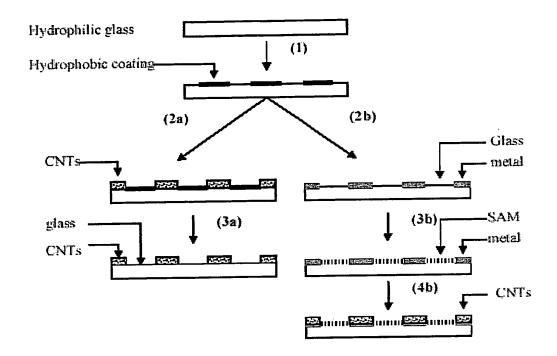


FIGURE 1B



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FIGURE 3A

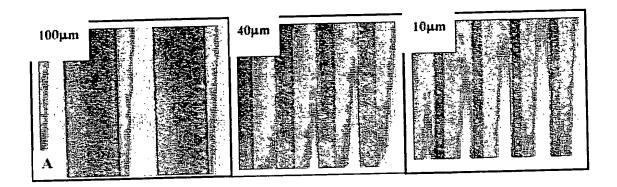
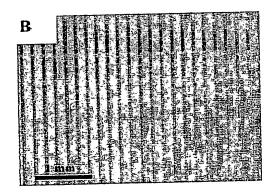
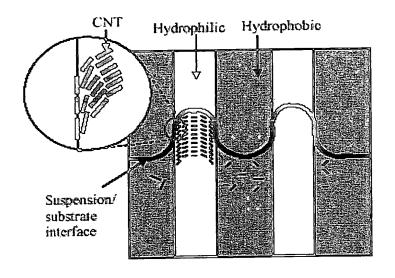


FIGURE 3B

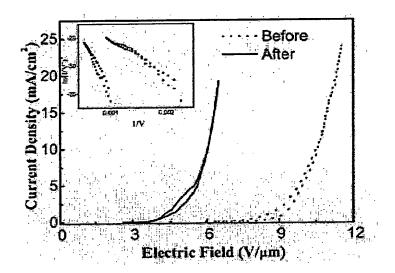


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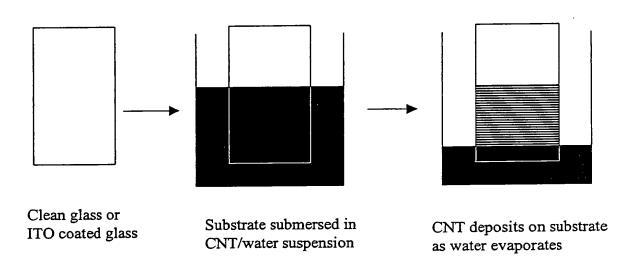


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FIGURE 7

ITO on glass Spin coat photoresist UV lithography with mask aligned with ITO pattern develop CNT film on ITO pattern Remove photoresist

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FIGURE 8

Glass or ITO coated glass

Self assembled monolayer of OTS

UV illumination in oxygen environment through photomask/mask

> Self assembled monolayer removed from UV illuminated area

CNT deposition on SAM cleared area

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